



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In Re	Application of)	
Hiroki et al.		I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313, 1450 on
Serial No.: 09/776,472)		
Filed: February 2, 2001		(Date of Deposit)
For:	Thin Film Formation Apparatus And) Method Of Manufacturing Self-Light-) Emitting Device Using Thin Film) Formation Apparatus)	Shannon Wallace Name of applicant, assignee, or Registered Rep. Shanwa Wallace Signature Date
Art Unit: 1762)		
Exam	niner: M. Cleveland)	
Com	missioner for Patents	
P.O. 1	Box 1450	
Alexa	andria VA 22313-1450	

AMENDMENT G (AFTER FINAL)

Sir:

In response to the Final Rejection of May 31, 2005, an RCE being submitted herewith, please amend the above-identified application as follows: